## Abstract

# METHOD AND DEVICE FOR TREATING SUBSTRATES AND CORRESPONDING NOZZLE UNIT

The invention relates to a method for treating substrates, which method comprises the following steps: producing a liquid film on a local surface area of the substrate to be treated using a nozzle unit which comprises at least one elongate nozzle arrangement and also using an ultrasound or megasound transducer arrangement arranged next to it; contacting at least a part of the ultrasound transducer arrangement with the liquid film; and introducing ultrasound into the liquid film produced using the ultrasound transducer arrangement.

No figure